



**INFORMATION DISCLOSURE  
STATEMENT BY APPLICANT**  
Form PTO-1449 (Modified)  
(Use several sheets if necessary)

**COMPLETE IF KNOWN**

Application Number	10/636,021
Confirmation Number	1017
Filing Date	6 August 2003
First Named Inventor	David A. Palsulich
Group Art Unit	2812
Examiner Name	(To Be Assigned)
Attorney Docket No.	108298727US

Sheet 1 of 2

**U.S. PATENT DOCUMENTS**

Examiner Initials*	Cite No.	U.S. Patent or Application		Name of Patentee or Inventor of Cited Document	Date of Publication or Filing Date of Cited Document	Pages, Columns, Lines, Where Relevant Passages or Relevant Figures Appear
		NUMBER	Kind Code (if known)			
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DATE CONSIDERED

4/27/05

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FOREIGN PATENT DOCUMENTS								
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		Office	NUMBER	Kind Code (if known)				
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OTHER PRIOR ART-NON PATENT LITERATURE DOCUMENTS				
Examiner Initials*	Cite No.	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume issue number(s), publisher, city and/or country where published.		T
EC	**	Solvay S.A., "Electricity and Electronics - Semiconductors," 2 pages, January 20, 2003, < <a href="http://www.solvasolexis.com/Semiconductors.htm">http://www.solvasolexis.com/Semiconductors.htm</a> >.		
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EXAMINER	<i>Eric Chen</i>	DATE CONSIDERED	4/27/05
*EXAMINER: Initial if reference considered, whether or not criteria is in conformance with MPEP 609. Draw line through citation if not in conformance and			